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APPLICANTS

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\*\* CONTINUING DATA \*\*\*\*\* *yes*  
 This application is a DIV of 10/079,262 02/21/2002 PAT 6,755,221

\*\* FOREIGN APPLICATIONS \*\*\*\*\* *yes*  
 REPUBLIC OF KOREA 2001-09045 02/22/2001

IF REQUIRED, FOREIGN FILING LICENSE GRANTED  
 \*\* 01/08/2004

Foreign Priority claimed 35 USC 119 (a-d) conditions met Verified and Acknowledged	<input checked="" type="checkbox"/> yes <input type="checkbox"/> no <input checked="" type="checkbox"/> yes <input type="checkbox"/> no <input type="checkbox"/> Met after Allowance Examiner's Signature <i>AK</i> Initials <i>13105</i>	STATE OR COUNTRY KOREA, REPUBLIC OF	SHEETS DRAWING 5	TOTAL CLAIMS 4	INDEPENDENT CLAIMS 1
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TITLE  
 Load port of a semiconductor manufacturing apparatus having integrated kinematic coupling pins and sensors, and method of loading wafers using the same

<input type="checkbox"/> All Fees
<input type="checkbox"/> 1.16 Fees ( Filing )